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Applied Materials, Inc.

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P. O. Box 450A, Santa Clara, CA 95052

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Date: February 8, 2005

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Phone:
Fax phone: 703-872-9306
CC:

From:
Emma Koh
Phone: (408) 986-3139
Fax phone: (408) 986-3090

REMARKS: Urgent For your review Reply ASAP Please comment

In Application of: Daniel J. Hoffman et al

Serial No.: 10/007,367

Confirmation No: 1261

Filed: 10/22/2001

Title: MERIE PLASMA REACTOR WITH OVERHEAD RF ELECTRODE TUNED
TO THE PLASMA WITH ARCING SUPPRESSION

Please receive a Petition For Revival Of An Application For Patent Abandoned Unintentionally Under 37 CFR 1.137(b) for above referenced application. Attached Fee Transmittal is faxed to the USPTO on this day, February 8, 2005..

Emma Koh

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